

### **IN THE ABSTRACT**

On page 28, please replace the current paragraph in the Abstract Of The Disclosure with the following new paragraph:

A method of making a magnetic head involves providing a partially constructed magnetic head which has a top surface formed by a front P2 pole tip, a back gap P2 pedestal, and insulator materials disposed between the front P2 pole tip and the back gap P2 pedestal; forming a layer of selectively etchable materials over the top surface of the partially constructed magnetic head, the layer having a front edge that is recessed away from an air bearing surface (ABS); forming additional insulator materials over the selectively etchable material layer and over a front portion of the front P2 pole tip; performing a chemical-mechanical polishing (CMP) to form a substantially coplanar top surface with the selectively etchable material layer and the additional insulator materials; etching to remove the selectively etchable material layer; depositing yoke layer materials over the resulting structure; and performing a chemically-mechanically polishing (CMP) to form a substantially coplanar top surface with the yoke layer materials and the additional insulator materials, to thereby form a yoke.